IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Re:

Application of Conni et al.4

Serial No.:

09/296,928

Filed:

April 22, 1999 L

CHEMICAL MECHANICAL

PLANARIZATION (CMP) SLURRY QUALITY CONTROL PROCESS AND

PARTICLE SIZE DISTRIBUTION

MEASURING SYSTEMS

Examiner:

Not Assigned

**Group Art Unit:** 2877

Docket No.:

7009/018CP

**CERTIFICATE OF MAILING(37 CFR 1.8)** 

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, DC 20231.

Nancy Halas

Assistant Commissioner for Patents Washington, DC 20231

## INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 CFR §1.97(c) and the duty of disclosure under 37 CFR §1.56, Applicant(s) submit the enclosed references and Form 1449 for consideration in the aboveidentified application.

The undersigned attorney believes that no fees are due, but authorizes the Commissioner to charge any additionally required fees to Deposit Account No. 04-1697.

> Respectfully submitted, DUFT, GRAZIANO, & FOREST, P.C.

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